

# Evaluation of Analog Parameters in SOI Nanowires nMOSFETs

Vinícius Rodrigues Prates and Michelly de Souza

Electrical Engineering Department, Centro Universitário FEI, São Bernardo do Campo, Brazil

unievprates@fei.edu.br, michelly@fei.edu.br

**Abstract**— This paper presents an analysis of analog parameters of SOI nanowires nMOS transistors through experimental data and numerical simulations results. The transconductance, output conductance and voltage gain are shown for different channel lengths and widths, for transistor biased at different gate and drain biases.

**Keywords**—nanowire transistors, SOI, electrical characterization, 3D numerical simulations

## I. INTRODUCTION

Increase of transistors density in a chip is one of the main goals in the semiconductor industry, since it can have a lot of benefits in the devices performance [1]. The principal way to reach this is by reducing the dimensions of the transistors. However, some effects appear in the transistors when the dimensions are tiny, called Shorts Channel Effects (SCE), such as threshold voltage and subthreshold slope degradation [2]. One way to circumvent these effects is the use of multiple-gate SOI transistors [3], such as the nanowire transistors. A schematic representation of a nanowire transistor is presented in Fig. 1. Due to the structure of Nanowires, which have the terminal of gate also at the sides of the channel, not only at the top like in planar MOSFETs, these undesirable effects diminish [3]. This improvement happens because of the great electrostatic control that the gate has over the channel, which reduces the influence of drain and source regions.

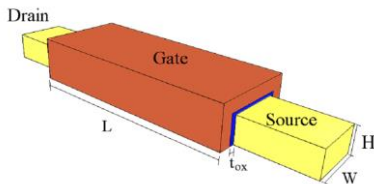


Fig. 1. Schematic view of a nanowire transistor.

The reduction of SCE in nanowires also improves the analog parameters, mainly the output conductance, which presents much lower values compared to planar SOI MOSFETs. Therefore, this paper analyzes three important analog parameters: transconductance ( $G_M$ ), output conductance ( $G_D$ ) and the intrinsic voltage gain ( $A_V$ ). The influence of nanowire width and length over these three parameters will be analyzed at different bias conditions, including subthreshold operation. The analysis is performed by means of 3D numerical simulations and experimental results.

## II. THREE-DIMENSIONAL NUMERICAL SIMULATIONS

Three dimensions numerical simulations using the Sentarus Device Simulator [4] were performed. Five models were considered: *IAlMob*, to consider mobility degradation in inversion layers; *Enormal*, that considers attraction of carriers in the interface of silicon and oxide with transversal electric field; *HighFieldSaturation*, that consider the effect of high electric field on the mobility; *DopingDep*, accounts for defects in the structure of the crystalline network; *OldSlotBoom*, that considers bandgap narrowing.

All devices were simulated at temperature of 300 K, with an oxide thickness ( $t_{ox}$  in Fig. 1) of 1.3 nm, channel doping of  $1 \times 10^{15} \text{ cm}^{-3}$  and a source and drain doping of  $5 \times 10^{20} \text{ cm}^{-3}$  and with channel height ( $H$ ) of 9 nm. The width ( $W_{FIN}$ ) has been varied between 10 and 20 nm (with length fixed in 20 nm and 40 nm), and length ( $L$ ) between 20 and 100 nm (with width fixed in 10 nm and 20 nm). For each simulated transistor  $I_D \times V_{GS}$  with  $V_{DS} = 0.5 \text{ V}$  to  $1 \text{ V}$  with step of 100 mV and  $I_D \times V_{DS}$  with  $V_{OV} = V_{GS} - V_t = -0.1 \text{ V}$  to  $0.2 \text{ V}$  with step of 100 mV were simulated. The threshold voltage ( $V_t$ ) was extracted individually using the double derivative method.

Figure 2 shows the  $I_D$  vs  $V_{GS}$  for six different drain voltages. Two transistors are shown: one with narrow and long channel ( $W_{FIN} = 10 \text{ nm}$  and  $L = 100 \text{ nm}$ ) and other with large and short channel ( $W_{FIN} = 20 \text{ nm}$  and  $L = 20 \text{ nm}$ ). As can be seen,  $I_D$  increases with the increase of  $V_{GS}$ , but the large and short channel device has a considerable increase before  $V_t$ , showing the loss of channel control by the gate. Furthermore, this transistor presents larger difference in the  $I_D$  curves in saturation with the  $V_{DS}$  change in comparison to the narrow and long device, something that is not supposed to happen, since in a first approximation  $I_D$  does not depend on  $V_{DS}$ .

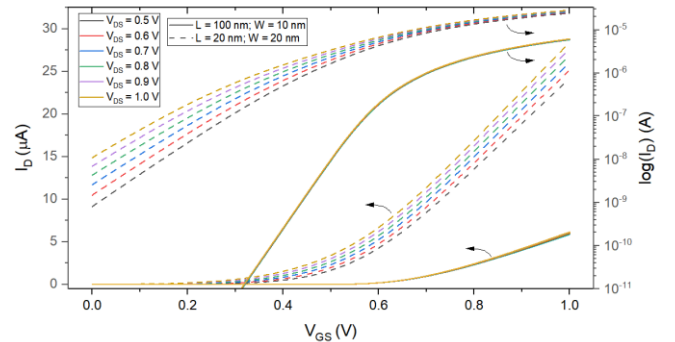


Fig. 2.  $I_D$  as a function of  $V_{GS}$ .

### A. Transconductance ( $G_M$ )

The transconductance defines the efficiency of the gate voltage ( $V_{GS}$ ) to control the drain current ( $I_D$ ) [5]. It is mathematically defined as the derivative of  $I_D$  by  $V_{GS}$ . In saturation, the  $G_M$  is defined by the equation 1.

$$G_M = \mu_e C_{ox} V_{ov} W / L \quad (1)$$

Figure 3 presents the transconductance vs.  $V_{GS}$  obtained from the derivative of the curves presented in Figure 2. The  $G_M$  vs.  $W_{FIN}$  with  $V_{DS} = 0.8 \text{ V}$  and  $V_{OV} = 0.1 \text{ V}$  is presented in Figure 4(A) for two channel lengths, 20 nm and 40 nm. From these results it is possible to see the linear increase of  $G_M$ , but with different slopes for different values of channel length, having the longer one a smaller slope,  $1.48 \mu\text{A}/\text{V}\cdot\text{nm}$  and  $1.04 \text{ A}/\text{V}\cdot\text{nm}$  for  $L = 20 \text{ nm}$  and  $40 \text{ nm}$ , respectively. The results of  $G_M$  as a function of  $L$  with the same polarization of  $V_{DS} = 0.8 \text{ V}$  and  $V_{OV} = 0.1 \text{ V}$  is presented in Figure 4(B). As can be seen, the transconductance increase highly with the decrease of the length, but the narrower channel presents smaller increase in  $G_M$  value.

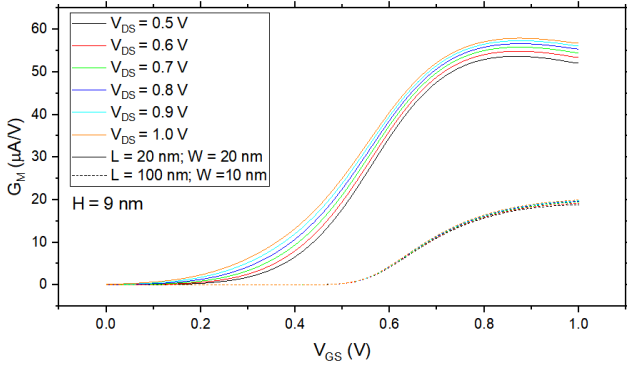


Fig. 3.  $G_M$  as a function of  $V_{GS}$ .

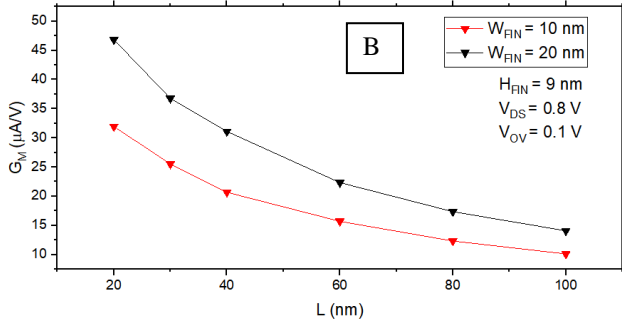
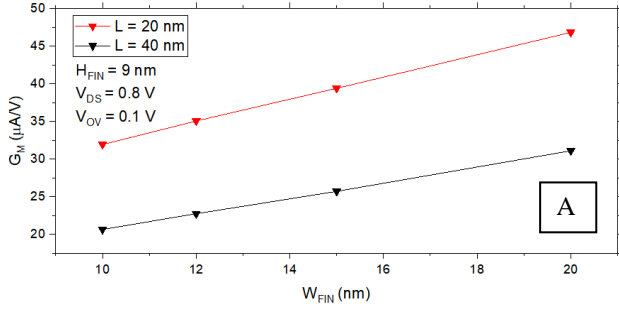


Fig. 4.  $G_M$  as a function of  $W_{FIN}$  (A) and  $L$  (B).

### B. Output Conductance ( $G_D$ )

The conductance defines the variation of drain current with drain voltage ( $V_{DS}$ ), i. e. the derivative of  $I_D$  by  $V_{DS}$  [5]. Ideally, the  $G_D$  is zero in saturation, however, due to channel length modulation (CLM), a short channel effect, the  $I_D$  increases with the drain voltage. The  $G_D$  can be described in saturation by the equation 2. As can be seen,  $G_D$  depends of the lambda parameter, but in nanowires devices this parameter is small, decreasing this parameter, becoming closer to the ideal.

$$G_D = \mu_e C_{ox} V_{ov}^2 \lambda W / 2L \quad (2)$$

The  $G_D$  as a function of  $V_{DS}$  with four gate voltages is shown in Figure 5, for the same devices shown in Figure 3. For both transistors  $G_D$  is different from zero, because of CLM. However, the transistor with narrow and long channel presents lower value of  $G_D$ , showing less shorts channel effects in this transistor. The curves of  $G_D$  as a function of  $W_{FIN}$  and  $L$  are presented in Figure 6, biased at  $V_{DS} = 0.8$  V and  $V_{OV} = 0.1$  V. The same tendency of  $G_M$  appears with the  $G_D$ , increasing its value with the increase of  $W_{FIN}$  and the decrease of  $L$ . This happens because both parameters depend on the relation  $L/W$ .

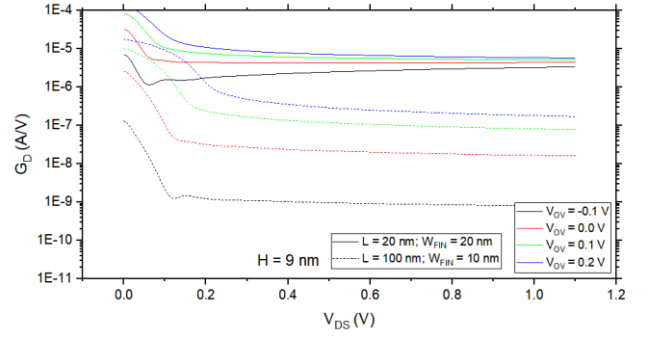


Fig. 5.  $G_D$  as a function of  $V_{DS}$ .

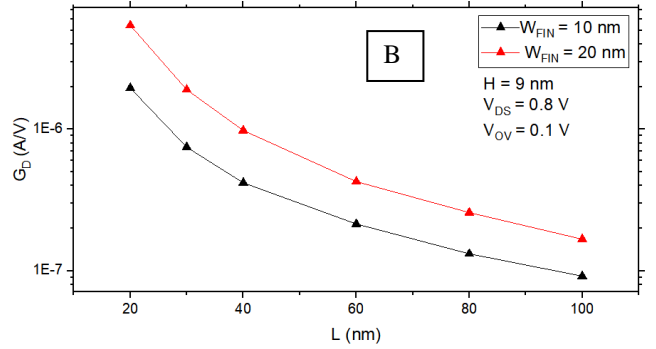
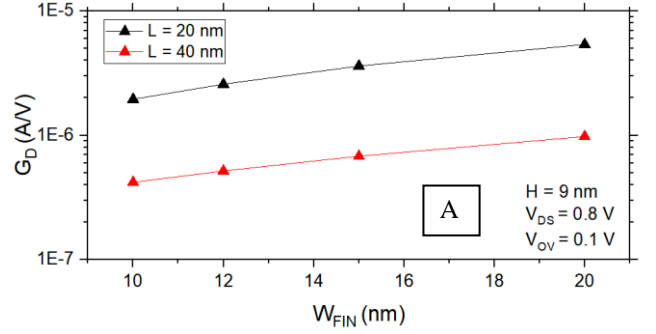


Fig. 6.  $G_D$  as a function of  $W_{FIN}$  (A) and  $L$  (B).

### C. Voltage Gain ( $A_V$ )

The voltage gain is an essential parameter in analog circuits such as amplifiers. It defines how much the voltage varies in the output with a variation in the input of the circuit. For MOSFETs biased in common-source configuration,  $A_V$  can be expressed by equation 3 [5]. As can be seen, the  $A_V$  depends inversely of  $G_D$ , showing that shorts channel effects harm this parameter.

$$A_V = G_M / G_D \quad (3)$$

Figure 7 shows the  $A_V$  as a function of  $V_{DS}$ , obtained using the curves presented in Figures 3 and 5. It is possible to see that the transistor with narrow and long channel presents a higher value of  $A_V$  compared to the transistor of large and short channel, due to the increase of gate control over channel promoted by the nanowire narrowing reducing the conductance and by consequence increasing the voltage gain. It can also be seen that the curve of  $V_{OV}$  present different tendency for each transistor. Transistor with short and large channel presents larger value of  $A_V$  when the  $V_{OV}$  is increased, while the transistor with long and narrow channel presents larger  $A_V$  with the smallest value of  $V_{OV}$ . So, there is a trend change in the curves of  $A_V$  with the change of the dimensions.

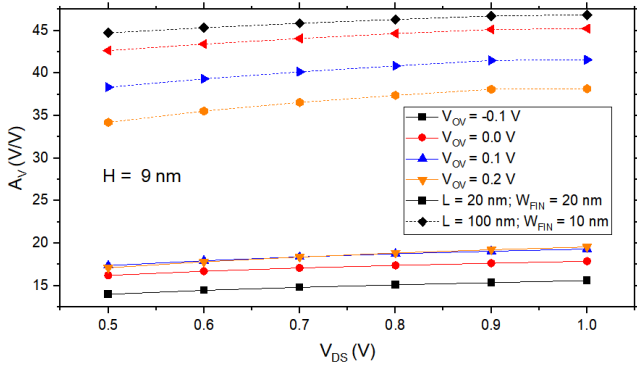


Fig. 7.  $A_V$  as a function of  $V_{DS}$ .

The Figure 8(A) shows the value of  $A_V$  vs.  $W_{FIN}$  with  $V_{DS} = 0.8$  V and different values of  $V_{OV}$ . The highest value of voltage gain occurs with small values of  $W_{FIN}$ , due to increased electrostatic control, and increases with  $V_{OV}$  reduction, approaching the subthreshold region. However, when the  $W_{FIN}$  increases,  $A_V$  decreases and a trend inverse occurs with  $V_{OV}$  change. The same trend change can be seen in Figure 8(B), where  $A_V$  as a function of  $L$  with  $V_{DS} = 0.8$  V and different  $V_{OV}$  is shown. However, in this curve the highest value of voltage gain occurs with high values of  $L$  (not with small values, like with the  $W_{FIN}$ ). In these cases, the reduction of  $V_{OV}$  increases the  $A_V$ , while in small values of  $L$  the reduction of  $V_{OV}$  decrease the voltage gain.

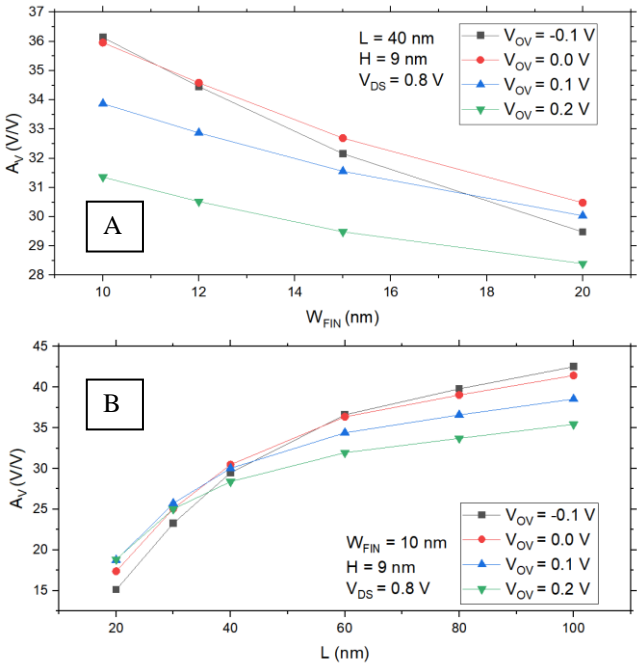


Fig. 8.  $A_V$  as a function of  $W_{FIN}$  (A) and  $L$  (B).

The presented results show that even with the transconductance the output conductance reduction with the increase of the  $L$  and the decrease of  $W_{FIN}$ , the voltage gain is benefited in these cases, indicating that  $G_D$  reduces much more than the  $G_M$ , increasing the  $A_V$  consequently.

### III. EXPERIMENTAL RESULTS

Electrical Measurements were made in chips produced by CEA-Leti [6]. The gate stack is composed of a thin interfacial  $\text{SiO}_2$  layer, followed by 2.3 nm  $\text{HfSiON}$ , 5 nm  $\text{TiN}$ , and 50 nm polysilicon. The effective oxide thickness (EOT) is around 1.4 nm. The channel region is not intentionally doped. Devices

present a fin height of 9 nm. The nanowire width ( $W_{FIN}$ ) has been varied between 12 and 222 nm (with length fixed in 40 nm and 100 nm), and length ( $L$ ) between 30 and 400 nm (with width fixed in 12 nm).

The  $G_M$  vs.  $V_{GS}$  and the  $G_D$  in function of  $V_{DS}$  are shown in the Figures 9(A) and 9(B), respectively. As in the simulation, transistors with short and large channel present bigger  $G_M$  but also a high difference in the curves with different  $V_{DS}$ . The  $G_D$  is also larger in transistors with short and large channel due to the short channel effects, as in the simulations.

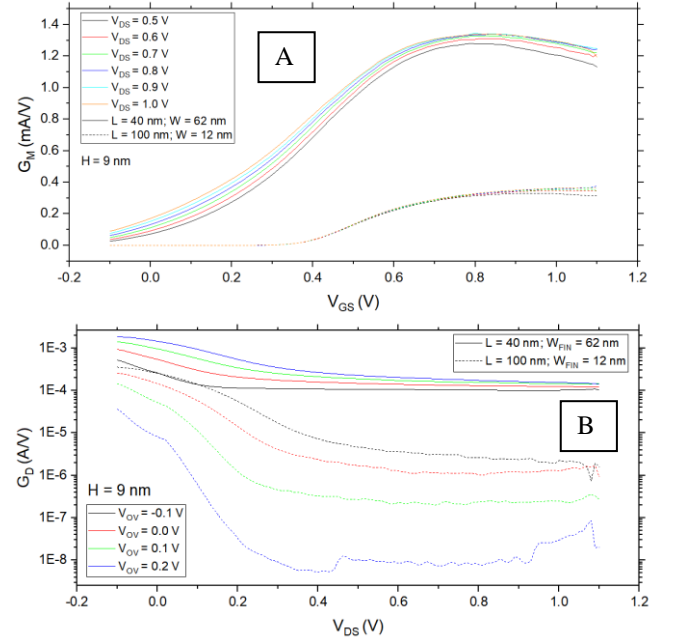


Fig. 9. Experimental curves of  $G_M$  vs.  $V_{GS}$  (A) and  $G_D$  vs.  $V_{DS}$  (B).

Figure 10 show the  $G_M$  and  $G_D$  vs.  $W_{FIN}$  for  $V_{DS} = 0.8$  V and  $V_{OV} = 0.1$  V and they present similar results to the simulations, having approximately a linear increase in the  $G_M$  and the  $G_D$  when the  $W_{FIN}$  increases, even with bigger values of width, which the simulation does not presents.

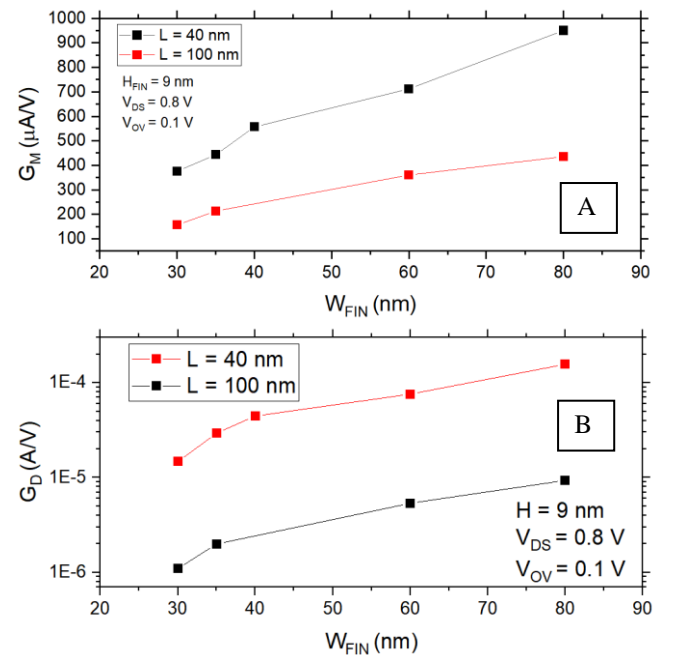


Fig. 10. Experimental results of  $G_M$  (A) and  $G_D$  (B) as a function of  $W_{FIN}$ .

The  $G_M$  and  $G_D$  vs.  $L$  with  $V_{DS} = 0.8$  V and  $V_{OV} = 0.1$  V is presented in Figure 11. The same tendency of increase of  $G_M$  and  $G_D$  when the  $L$  decrease appears in the experimental results, even with large values of  $L$ .

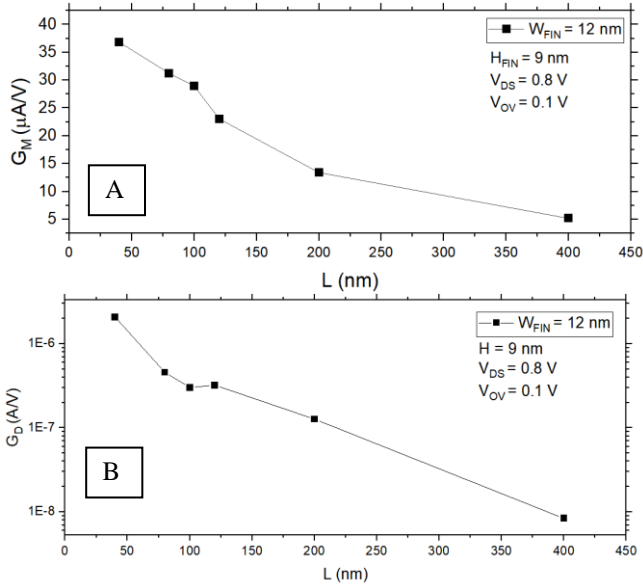


Fig. 11. Extracted values of  $G_M$  (A) and  $G_D$  (B) as a function of  $L$ .

Figure 12 shows the  $A_V$  vs.  $V_{DS}$  for two different transistors, being one with  $L = 200$  nm and  $W_{FIN} = 12$  nm and the other with  $L = 40$  nm and  $W_{FIN} = 62$  nm, both presenting four different gate bias. It can be seen difference tendencies for the two transistors: the transistor with narrow and long channel presents the higher voltage gain with the  $V_{OV} = -0.1$  V, while the transistor with large and short channel presents a higher voltage gain with the  $V_{OV} = 0.2$  V. Furthermore, the transistor with narrow and long channel presents a higher value for all polarization compared to the other transistor.

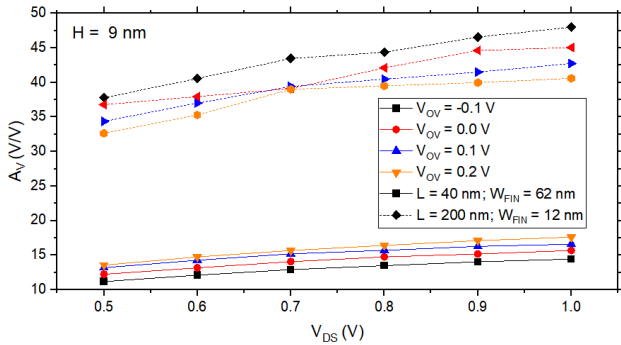


Fig. 12.  $A_V$  as a function of  $V_{DS}$ .

Figure 13 shows the  $A_V$  vs.  $W_{FIN}$  and  $L$ . It is possible to see that for small values of  $W_{FIN}$  the  $A_V$  shows a large increase and that the  $V_{OV}$  reduction increases  $A_V$ , whereas large nanowires show higher gain with larger  $V_{OV}$ .

#### IV. CONCLUSIONS

This paper presented the influence of nanowires transistors dimensions in analog parameters using 3D numerical simulations and electrical measurements. It was shown that the transconductance and output conductance presented the same tendency of decrease when channel length is increased and when the width is decreased. The reduction of width increases electrostatic control, improving output conductance. At the same

time, transconductance reduces due to the total width reduction. An  $A_V$  increase has been observed in those cases. This happens due to the fact that the  $G_D$  reduces more than the  $G_M$  due to the structure of nanowire that improves the control of the gate over the channel, reducing the channel modulation effect. It was also shown that the voltage gain dependence on  $V_{OV}$  depends on the channel dimensions. The results showed that when the channel is long and narrow, larger gain is obtained when the transistor operates in the subthreshold region, with a negative gate voltage overdrive. When the channel is large and short, the highest  $A_V$  is reached for higher  $V_{OV}$  values. So, narrow and long channel operating in subthreshold region presents the best analog characteristics since the gain voltage is higher and presents a lower power consumption.

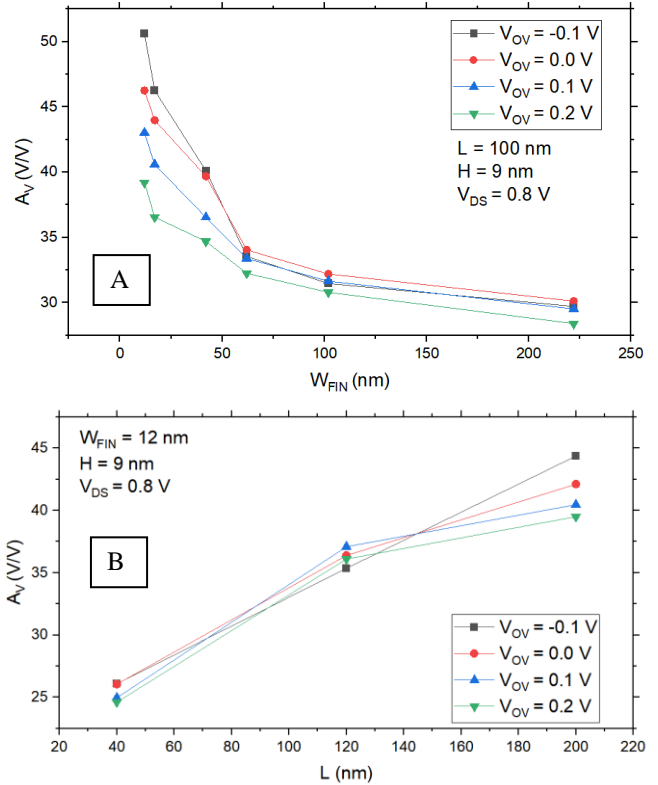


Fig. 13. Experimental  $A_V$  as a function of  $W_{FIN}$  (A) and  $L$  (B).

#### ACKNOWLEDGMENT

Vinícius Prates acknowledges to FAPESP for the financial support to do this work (Project number 2021/02993-3).

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